

--ABSTRACT

[The present invention provides a] A ceramic heater which makes it possible to make the distance between a semiconductor wafer and the heating surface of a ceramic substrate constant at any time, heat the semiconductor wafer at an even temperature, and prevent contamination of the semiconductor wafer, and which does not cause dropping-out of a supporting pin. The ceramic heater [of the present invention comprises] includes a ceramic substrate on a surface of which or inside which a heating element is formed, wherein the ceramic heater is constituted to have a structure such that an object to be heated can be held apart from a surface of [said] the ceramic substrate and heated.--

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